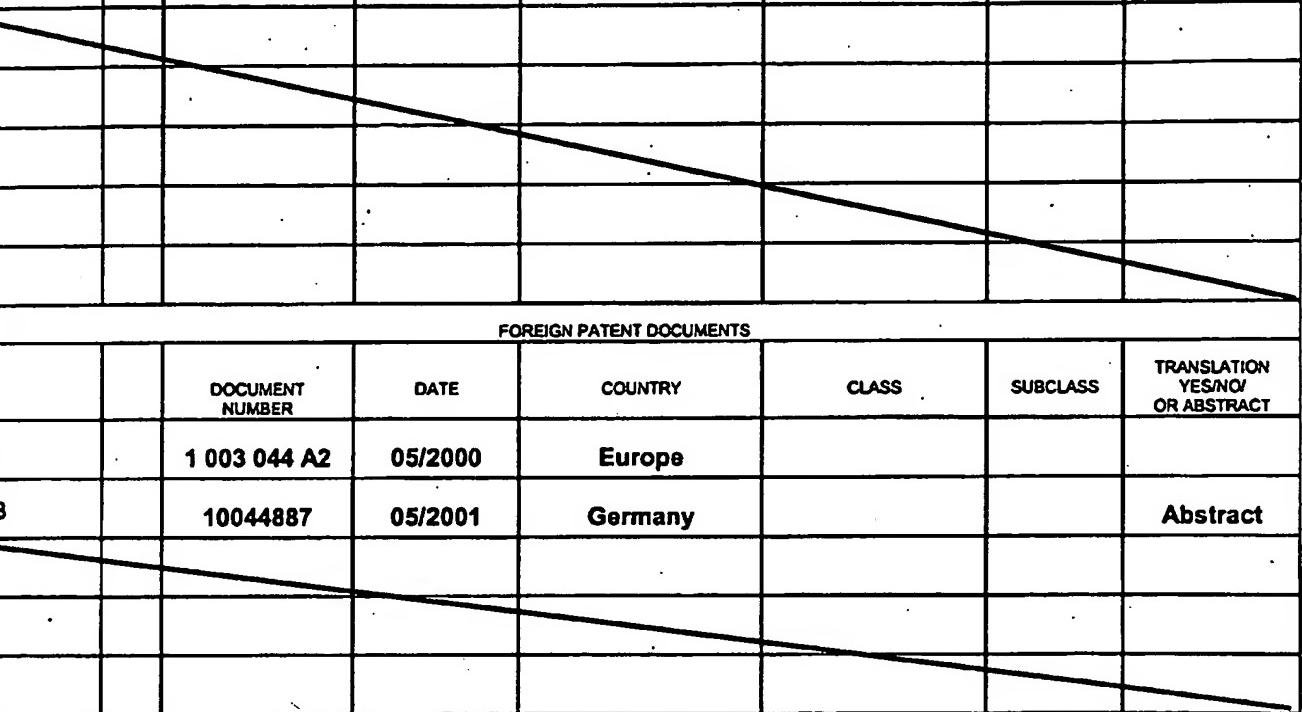


FORM PTO 1449 (modified) IDS - 11/06/2006 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 03500.017988.	APPLICATION NO. 10/551,112			
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)		APPLICANT Susumu Yasuda, et al.				
		FILING DATE September 28, 2005	GROUP 2858			
US PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
WB	2003/0057977	03/2003 Werner, Jr. et al.	324	754		
WB	2006/0171728	08/2006 Ichimura et al.	399	48		
WB	2006/0186898	08/2006 Ichimura et al.	324	663		
						
FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
WB	1 003 044 A2	05/2000	Europe			
WB	10044887	05/2001	Germany			Abstract
						
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)						
WB	Richl, P. S., "Microsystems for Electrostatic Sensing", Dissertation, Nov. 2002, pp. 1-8, 32-40, 79-84.					
WB	Hsu, C. H. et al., "Micromechanical Electrostatic Voltmeter", Proc. Int'l. Conf. on Solid State Sensors and Actuators, NY, IEEE, US, vol. 6, 24, June 1991, pp. 659-662					
EXAMINER		/Walter Benson/	DATE CONSIDERED	01/07/2007		

**EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.*

Sheet 1 of 1

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Sheet 1 of 1

Form #62

CA_MAIN 124174v1